AP20 Rec'd PCT/PTO 28 JUN 2006

PATENT APPLICATION

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of

Isao YOKOKAWA

Application No.: New U.S. Patent Application

Filed: June 28, 2006 Docket No.: 128503

For: METHOD FOR MEASURING AN AMOUNT OF STRAIN OF A BONDED STRAINED

WAFER

INFORMATION DISCLOSURE STATEMENT

Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

Sir:

Pursuant to 37 CFR §1.56, the attention of the Patent and Trademark Office is hereby directed to the references listed on the attached PTO-1449. Unless otherwise indicated herein, one copy of each reference is attached. It is respectfully requested that the information be expressly considered during the prosecution of this application, and that the references be made of record therein and appear among the "References Cited" on any patent to issue therefrom.

- 1. This Information Disclosure Statement is being filed (a) within three months of the U.S. filing date of this non-CPA application, OR (b) before the mailing date of a first Office Action on the merits in the present application. No certification or fee is required.
- 2. Relevance of one or more non-English language reference is discussed in the present specification. See References 1 3 and 8.
- 3. One or more reference cited herein was cited in the International Search Report. A copy of the International Search Report is attached for the Examiner's information. According to the Notification of Acceptance in this file, a copy of each reference is already in the PTO file. Thus, no copy of any such reference is attached. See References 4 7 and 9.
- 4. An English language Abstract of one or more non-English language reference is attached hereto. See References 1 7.

New U.S. National Phase of PCT/JP2005/000165

5. A computer-generated English language translation of one on more Japanese N 2006

Patent Publication cited herein has been obtained from the website of the Japanese Patent

Office ([http://www.jpo.go.jp]), and is attached, but has not been reviewed for accuracy.

See References 1 - 7.

Respectfully submitted,

William P. Berridge

Registration No. 30,024

Joel S. Armstrong Registration No. 36,430

WPB:JSA/jtp

Date: June 28, 2006

OLIFF & BERRIDGE, PLC P.O. Box 19928 Alexandria, Virginia 22320 Telephone: (703) 836-6400 DEPOSIT ACCOUNT USE
AUTHORIZATION
Please grant any extension
necessary for entry;
Charge any fee due to our
Deposit Account No. 15-0461

14P20 Rec'd PCT/PTO 28 JUN 2006

Sheet Form PTO-1449 US Dept. of Commerce ATTY DOCKET NO. PATENT & TRADEMARK OFFICE (REV. 1/06) 128503 INFORMATION DISCLOSURE STATEMENT (Use several sheets if necessary) APPLICANT Isao YOKOKAWA **GROUP** FILING DATE June 28, 2006 U.S. PATENT DOCUMENTS Examiner Cite Document Number Date Name Initials No. FOREIGN PATENT DOCUMENTS With Cite With Examiner English English Initials No. Document Number Date Country Abstract Translation 1 JP A 2001-217430 8/10/2001 Japan Х Х 2 JP A 2002-164520 6/7/2002 Х Х Japan 3 10/18/2002 Х \mathbf{X} JP A 2002-305293 Japan 4 JP A 2003-229360 8/15/2003 Japan Х Х 8/15/2003 Х х 5 JP A 2003-229361 Japan х X 6 JP A 2000-286413 10/13/2000 Japan 7 JP A 11-304729 11/5/1999 Japan Х Х OTHER DOCUMENTS Cite (Including Author, Title, Date, Pertinent Pages, etc.) Examiner Initials No. M. Erdtmann et al, "Structural Characterization of Strained Silicon Substrates by X-Ray Diffraction and Reflectivity", Extended 8 Abstracts of the 2003 International Conference on Solid State Devices and Material, Tokyo, pp. 290-291, 2003. 9 W.L. Bond, "Precision Lattice Constant Determination", Acta Crystallographica, pp. 814-818, October 10, 1960. **EXAMINER DATE CONSIDERED**

Initial if citation considered, whether or not citation is in conformance with M.P.E.P. 609; draw line through citation if not in conformance

and not considered. Include copy of this form with next communication to applicant.

Date: June 28, 2006

Examiner: